

The Latest Progress of 45 GHz FECR

L. Sun

H. W. Zhao, W. Wu, W. Lu, J. B. Li, X. Y. Wang, B. M. Wu, X. J. Ou, E. M. Mei, S. J. Zheng, L. B. Li, X. Z. Zhang, L. Zhu, C. J. Xin, Y. Q. Chen and the other FECR team members *Institute of Modern Physics, CAS, 730000, Lanzhou, China*

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□Global needs on HCI beams production

DProgresses with the 3rd G ECRISs and the

challenges

□Status of FECR development

DSummary





Global needs on HCI beams









GSI FAIR (under construction)





IMP HIAF (under construction)

Global needs on HCI beams



Global needs on HCI beams



















More to come:

- 28 GHz SECRAL-III@IMP
- 28 GHz ASTERICS@GANIL
- 28 GHz SC-ECRIS@JINR

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VENUS@LBNL: 28+18 GHz

SCECRISs@RIKEN: 28+18 GHz





SECRAL-I, SECRAL-II@IMP: 28/24+18 GHz







Challenges
High frequency high power coupling to ECR plasma
Efficient cooling to hot dense plasma
Refractory metallic ion beam production



Efficient microwave coupling



L. Sun, et al., Review of Scientific Instruments 87, 02A707 (2016);

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Efficient microwave coupling via WG opening tuning:

- Ø20 mmTE₀₁ show obvious advantage in HCI production at high power level
- No sign of saturation even at high power level





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Progresses with the 3rd G ECRISs and the challenges

Efficient microwave coupling





J.W.Guo, et al., Rev. Sci. Instrum. 91, 013322 (2020)



Power density on 1st ECR surface









Efficient microwave coupling

- Vlasov launcher is an efficient tuner to microwave plasma coupling
- µW radiation <P> distribution might be a key to efficient HCI production
- Recorded beam intensities production:

18 eµA Xe⁴²⁺、 47 eµA Xe³⁸⁺、

146 eμA Xe³⁴⁺、374 eμA Xe³⁰⁺

Xinyu Wang@Poster session on Monday







Efficient Chamber Cooling

Maximum permissible operating power exceeds 10 kW

Chamber ID:125 mm, Microchannel:0.4 mm *20, Channel height:1.5 mm, Channel flow rate: 4 L/min







7 Before After 6 Operation µW Power (kW) Previous safe operation power 0 40 78 129 209 Ion Mass

Efficient Chamber Cooling

Routine safe operation power obviously increased with new chamber structure

Reliable long-term operation at 5~10 kW level applicable



Server etching marks after continuous high power Ar beam operation







HIRFL Operation scheme: ECR + Cyclotron + Synchrotron





HIRFL performance enhancement

SECRAL-II: ~350 eµA (~4 times historical operation current)

- High current: SFC--8.5 AMeV/15 eµA
- CSR_m Beam Current Increase by a factor of 5

⁷⁸Kr²⁶⁺

36**A**r¹⁵⁺

SECRAL-II: ~280 eµA (not available before)

- High current: SFC--6 AMeV/12 eµA
- CSR_m Beam Current Increase by a factor of 10

¹²⁹Xe³²⁺

SECRAL-II: ~200 eµA (not available before)

- High current : SFC—3.9 AMeV/8 eµA
- CSR_m Beam Current Increase by a factor of 5









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Progresses with the 3rd G ECRISs and the challenges

High temperature inductive heating oven



- Metallic ions delivered from LECR5 (2021-2023): ⁴⁰Ca¹³⁺, ⁵⁵Mn¹⁷⁺, ⁵⁴Cr¹⁷⁺, ⁴⁸Ca¹⁴⁺;
- RF Power: 18+14.5 GHz/ 1.5- 2.0 kW
- IS extraction voltage: 30.8- 34.2 kV
- Technical features:

Inductive heating oven, CaO+Al



RT ECR ion source - LECR5

FQ entrance Transmissio Delivering
RMS n efficiency time
emittance [FC03/FC01] [Hrs]
π.mm.mard)
ξx=0.12, 85~90% 1500 ξy=0.05
£x=0.08, 85~90% 428 £y=0.06
£x=0.08, 85~90% 1183 £y=0.06
Ex=0.09, 85~90% ~600 Ey=0.08
2



Technologies advancement with intense U beam production













- **Material:** $UO_2 + O_2$
- Frequency: 24+18 GHz
- RF power: ~7.9 kW
- Total drain: ~13.2 emA





U Charge State	SECRAL-2023 (eµA)	Records as of 2022 (eµA)	Contributors as of 2022
33	640	450	SECRAL-II/IMP ¹
34	620	400	VENUS/LBNL ²
35	547	310	VENUS/LBNL,SECRAL-II/IMP
42	100	62.6	SCECRIS/RIKEN ³
46	61	36.2	SCECRIS/RIKEN
50	38	20.1	SCECRIS/RIKEN
54	19	10.4	SCECRIS/RIKEN
56	9.5	0.9	SECRAL-II/IMP
58	2.7	0.7	SECRAL-II/IMP

1. W. Lu et al., Rev. Sci. Instrum. 90, 113318 (2019)

- 2. J. Benitez, et al., ECRIS2012, THX002-talk
- 3. T. Nakagawa, Cyclotron'22, invited talk











Specs.	Unit	3 rd G ECRIS	4 th G ECRIS	FECR
frequency	GHz	24-28	40~56	45
Operational RF Power	kW	4~10	10~40	20
B _{ECR}	Т	0.86~1.0	1.4~2.0	1.6
B _{rad}	Т	1.8~2.2	2.8~4.0	≥3.2
\mathbf{B}_{inj}	Т	3.4~4.0	5.6~8.0	≥6.4
\mathbf{B}_{\min}	Т	0.5~0.7	/	0.5~1.1
B _{ext}	Т	1.8~2.2	3.0~4.5	≥3.4
B _{max} in conductor	Т	~7.0	>10.0	11.8
Plasma Chamber ID	mm	100~150	>100	≥140
Mirror Length	mm	420~500	≥500	500
Cooling Capacity@4.2 K	W	0~6.0	>10.0	≥10.0







Nb₃Sn vs. NbTi:

- Fragile
- Treatment sensitive
- Stress sensitive

Courtesy of MagLab









AXIAL RODS

The magnet mechanical structure was designed by collaboration with ATAP magnet group at LBNL as of 2017



This Nb₃Sn magnet is being built by a Chinese company without collaboration with ATAP/LBNL. DOE did not approve such collaboration.





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8 sextupole coils for full assembly











Completed FECR coldmass





• Stress on Wire: Improper handling and failing to protect the coil leads



• Intense Flux Jump (FJ) Interference: challenging in fast quench detection









Hybrid coils:

- NbTi sextupole + Nb₃Sn solenoids
- Intense FJ mitigation
- Assembly test
- Operation safe
- Nb₃Sn Sextupole with cable in progress



NbTi sextupole coils





Sub-assembly of the cold mass





Key parameters of FECR Cryogenic System

Parameters	Value	Note
Operation Temp. (K)	4.3 K	
Magnet Cooling	LHe bathing and "O" boiling-off	
Stored Energy (MJ)	~1.6	100% currents
Required heat load (W)	≥ 12	~2 W static at 100% currents
Warm Bore (mm)	Ø162	
LHe Volume (L)	~330	
Cryocoolers	6 two-stage + 1 single stage coolers	Cold service enabled
Dimension (mm)	L1456 $ imes$ Ø1200 $ imes$ H2690	
Total weight (ton)	~6.1	

















Key Parameters	FECR Chamber	SECRAL-II Chamber
Max. Microwave Power	25 kW	12 kW
Max. Localized Power Density	20 MW/m ²	10 MW/m ²
Chamber ID	Ø140 mm	Ø125 mm
Chamber OD	Ø156 mm	Ø136 mm
Length	1225 mm	887 mm
Microchannel region	15×15.6×1.5 mm ³	15×15.6×1.0 mm ³
Fins	0.4 mm×19	0.4 mm×19
Channel	0.4 mm×20	0.4 mm×20
Inside-wall thickness	1.5 mm	1.5 mm
Outside-wall thickness	1.5 mm	1.5 mm
Water pressure	10 bar	8.9 bar
Water flow per channel	> 15 L/m	> 4.0 L/m
Total water flow	> 50 L/m	> 13 L/m











- Technical advancement makes intense HCI beams production feasible and durable
- New records on highly charged ion beams production
 - ✓ 620 еµА U³⁴⁺, 547 еµА U³⁵⁺, …
 - ✓ 18 еµА Хе⁴²⁺、 47 еµА Хе³⁸⁺、 146 еµА Хе³⁴⁺、 374 еµА Хе³⁰⁺
- FECR development still having challenges in terms of Nb₃Sn magnet





Acknowledgement



Xi'an Superconducting Magnet Technology Inc.

Coil fabrication

Cold mass fabrication and assembly



Bruker OST LLC.

• Nb₃Sn Wire



Western Superconducting Tech Co., Ltd.

- Nb₃Sn Wire
- Wire braiding



Lanzhou Kejin Taiji New Technology Co., Ltd.

Mirror structureMechanical mapping



Lawrence Berkeley National Laboratory

Coldmass structure design



Shanghai Chenguang Medical Technologies Co., Ltd.

Cryogenic system fabrication and integration



GyCOM Co., Ltd.

• Gyrotron microwave generator and microwave transmission solutions

And all those have given us fruitful suggestions!!

